

INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Application No.	10/683,727
	Filing Date	October 10, 2003
	First Named Inventor	Arthur Sherman
	Art Unit	1792
(Multiple sheets used when necessary)	Examiner	Gambetta, Kelly M.
SHEET 1 OF 1	Attorney Docket No.	ASMMC.9CP1DV1C1

U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No.	Document Number Number - Kind Code (if known) Example: 1,234,567 B1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
	1	3,660,179	05-02-1972	Desmond et al	
	2	5,458,733	10-17-1995	Tessmer et al.	
	3	6,426,273	07-30-2002	Toshiharu Yanagida	
	4	6,645,574	11-11-2003	Lee et al.	
	5	6,784,782	10-15-2002	Sivaramakrishnam et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Foreign Patent Document Country Code-Number-Kind Code Example: JP 1234567 A1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear	T ¹
	6	WO 00/63957	10-26-2000	Genitech, Inc.		

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ¹
	7	CATHERINE et al., Plasma Deposition of Aluminum Oxide Films, J. Elec. Mat., 1988, Vol. 17 (2), Pages 127- 134	
	8	EHLE et al., Low Temperature Aluminum Oxide Deposition Using Trimethylaluminum, J. Elec. Mat., 1982, Vol. 12(3), Pages 587-601	

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Examiner Signature	Date Considered
<p>*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>	

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